



Recent Advances in Optoelectronic Devices and Materials in South Korea

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Message from the Guest Editor

Dear Colleagues,

Rapid advances in the field of materials science provide opportunities to produce high-performance optoelectronic device applications. Emerging materials such as nanomaterials (e.g., one-dimensional semiconducting carbon nanotubes and two-dimensional semiconducting graphene analogs such as transition metal dichalcogenides, black phosphorus, etc.) and halide perovskites can be considered as leading successors to the conventional silicon-based material system for high-performance optoelectronic device applications including photodetectors, light-emitting diodes, photovoltaics, and lasers.

The Special Issue on “Recent Advances in Optoelectronic Devices and Materials in South Korea” brings together contributions from Korean scientists working on emerging materials and their optoelectronic applications to provide an overview of the current state-of-the-art research. The main topics of the Special Issue will cover emerging nanomaterials, nanomaterials processing, and optoelectronic devices.

We look forward to receiving your submissions!





Editor-in-Chief

Message from the Editor-in-Chief

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